

## IN THE CLAIMS

1. - 15. (Cancelled)

16. (New) A method of manufacturing an electron source panel having a plurality of electron emitting devices disposed on a substrate, comprising the steps of:

measuring electron emission characteristics of each of the electron emitting devices and setting a characteristics adjustment target value;

applying a plurality of characteristics shift voltages having discrete values to some of the electron emitting devices not contributing to an image display;

measuring electron emission characteristics of the electron emitting devices not contributing to the image display and creating a characteristics adjustment table for each of the values in accordance with an average of change rates of measured electron emission characteristics of the electron emitting devices not contributing to the image display; and

selecting a predetermined characteristics shift voltage value from the plurality of characteristics shift voltage values by referring to the characteristics adjustment table created for each of the electron emitting devices and applying the predetermined characteristics shift voltage value to the electron emitting devices to shift the characteristics toward the characteristics adjustment target value.

17. (New) The method according to claim 16, wherein the step of measuring electron emission characteristics of each of the electron emitting devices includes measuring a luminance of a phosphor emitting light responsive to an irradiation with an electron emitted from the electron emitting devices.

18. (New) The method according to claim 16, wherein the electron emitting devices not contributing to the image display are dummy devices not driven in an image display.